

A B S T R A C T

An exposure apparatus comprises a container-mount, on which a holder container that can contain a substrate holder in a sealed manner and that has a door is mounted, the door being able to open and close; an open-close mechanism that opens and closes the door in a manner that the inside of the container mounted on the container-mount is isolated from the outside; and a transport system that exchanges such a holder on a stage with another holder in the container when the open-close mechanism has opened the door. Therefore, the transport system can exchange such holders in a short time in a manner that the inside of the apparatus is isolated from the outside. Accordingly, the down time of the apparatus can be shortened, and the cleanliness of the holders can be maintained all the time. As a result, the productivity of devices such as semiconductor devices can be improved.